

MPI TS50 | 50 mm Manual Probe System

For accurate and reliable DC/CV and RF measurements

Microscope and Optics Options

- Various optics options available
- Stereo MPI ST45 or single tube MPI SZ10 with up to 10x zoom and 95 mm working distance
- HDMI cameras, monitor user interface without computer

Microscope Mount and Movement

- Stable bridge for high quality optics
- Microscope pivot XY movement
- 50 mm linear Z with the focus block

Adjustable Platen Height

- Micrometer control for precise adjustment
- 20 mm range for various applications

Probe Platen

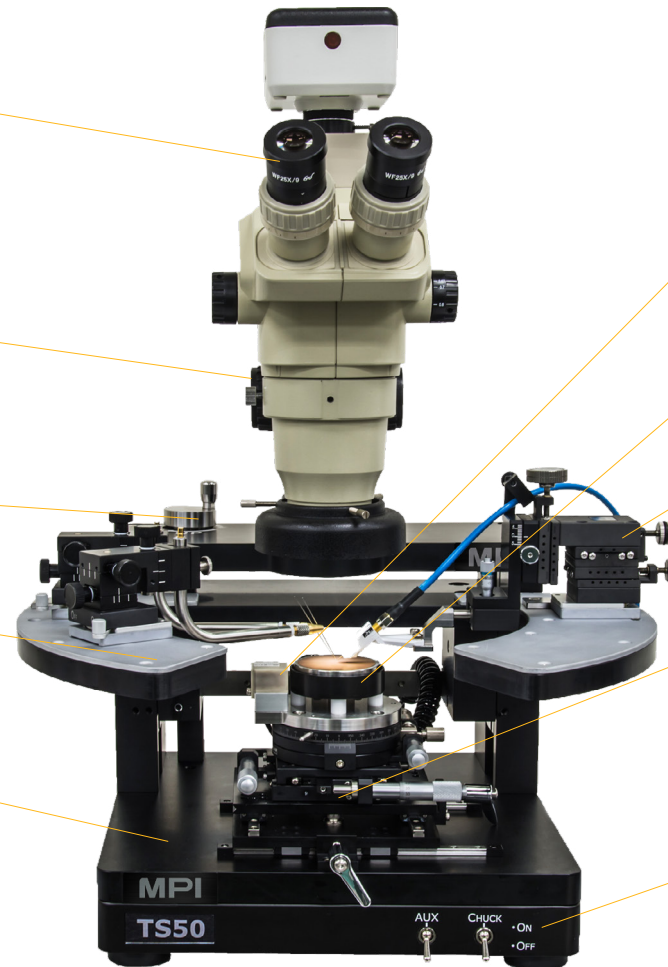
- Stable and rigid design
- Supports DC/CV and RF measurements
- Rectangular adjustments for RF positioners

Ultra Small Footprint

- 300 x 300 mm base plate designed for bench top use
- Comes with vibration absorber base
- Low profile design for maximum usability
- Ideal for load pull applications

Available Options

- Vibration isolation platform
- EMI-shielded DarkBox
- Vacuum pump
- Table with integrated rack for thermal controller, computer and keyboard push tray
 - Dual monitor stand option
 - Instrument shelf option



RF Calibration

- Auxiliary chuck for calibration substrates
- Built-in ceramic for accurate calibration
- 1 μ m flatness for consistent contact quality

Modular Chucks

- Non-thermal chucks
- Supports DC/CV and RF applications

DC and RF Positioners

- Supports 2-port RF and up to 6 DC positioners
- Wide range of positioners available
- Dedicated probe arms for DC/CV and RF measurements

Chuck XY-Theta Stage Movement

- 100 x 75 mm XY movement
- Including 25 x 25 mm fine micrometer control
- $\pm 5^\circ$ Theta fine adjustment
- Quick release function
- Independent fast XY navigation

Front Mounted Vacuum Control

- Easy access
- Clearly marked